

FIG. 1

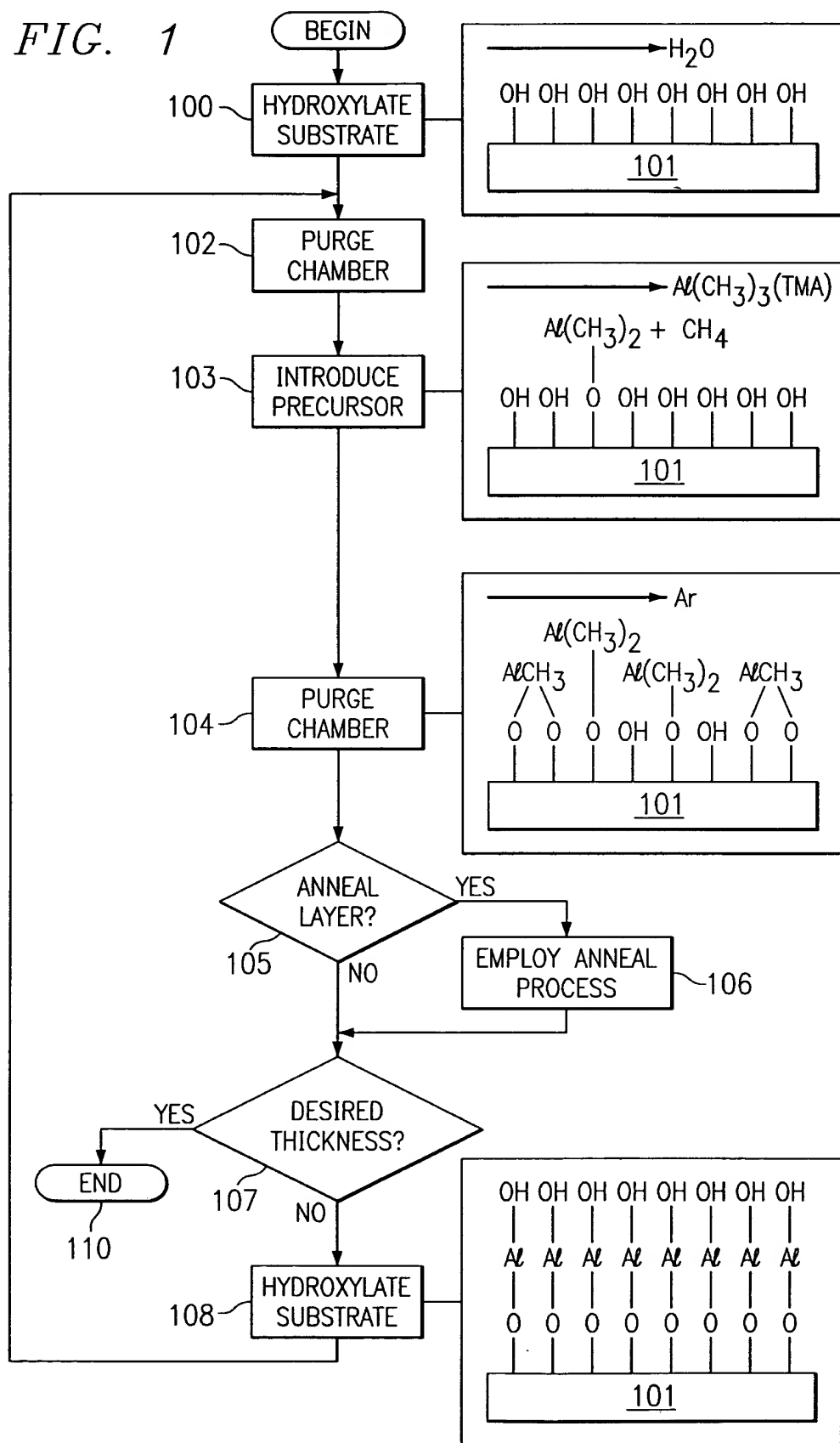
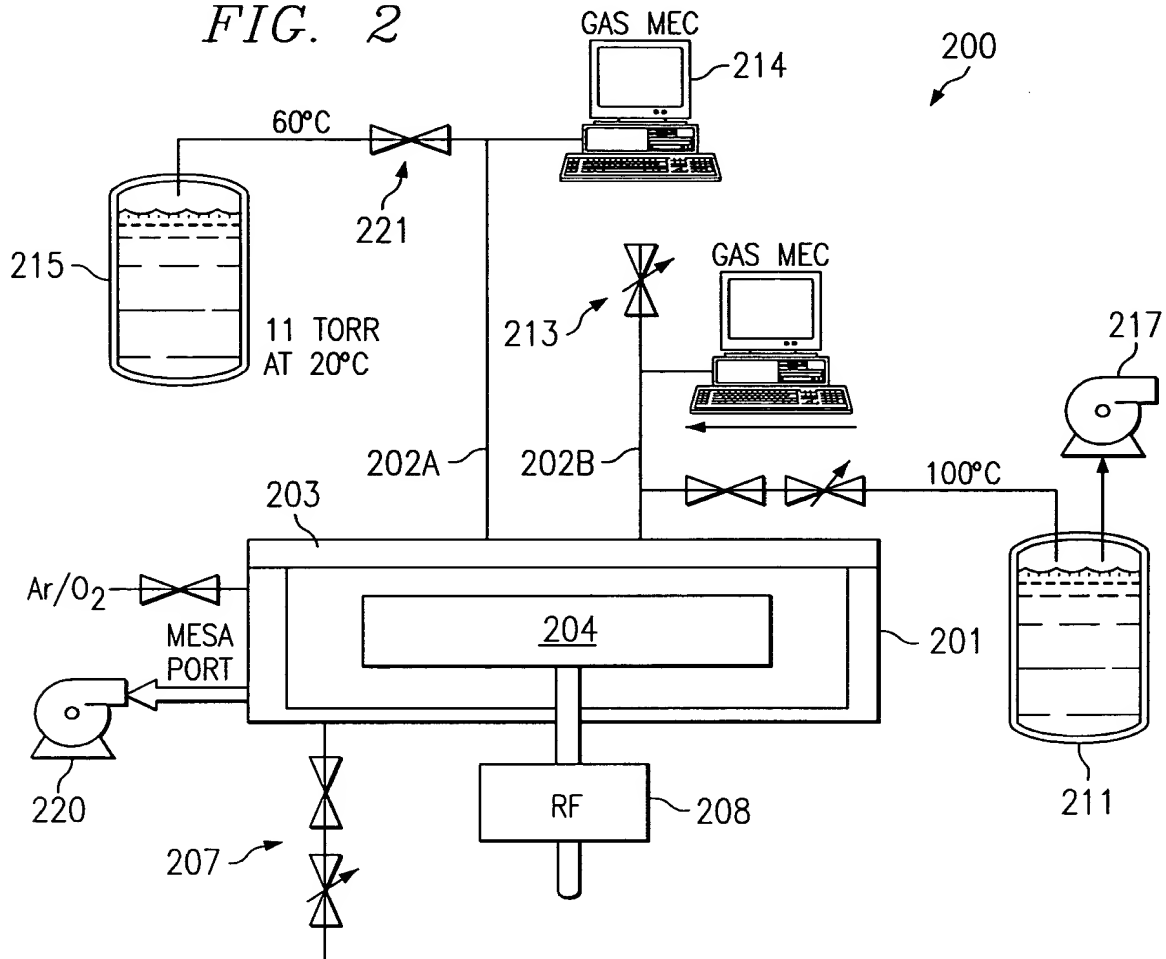


FIG. 2



300

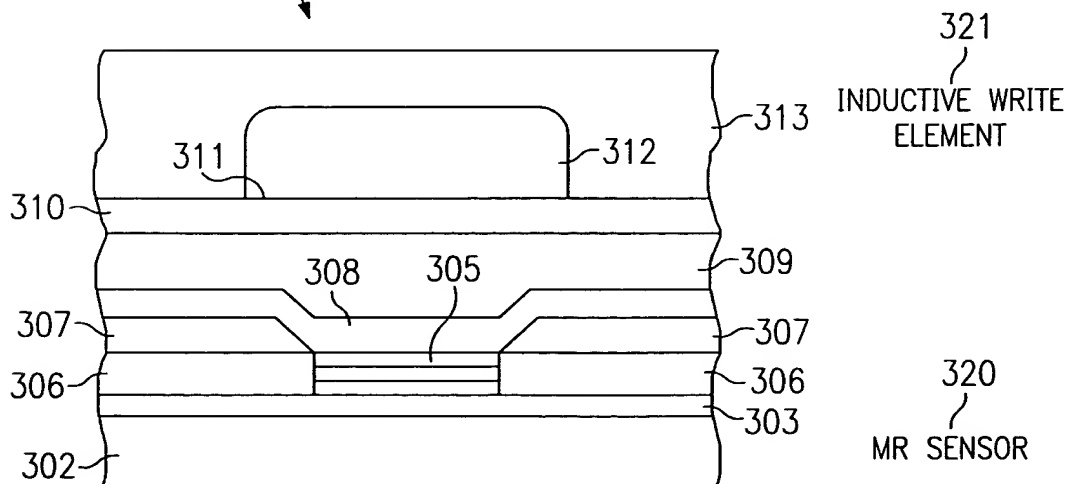


FIG. 3

REVISED	O.G. FIG.
BY	CLASS
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ATOMIC LAYER DEPOSITION FOR FABRICATING THIN FILMS

Inventor: Ajit P. Paranjpe, et al.

Express: EL740056656US

Docket: 021208.0238

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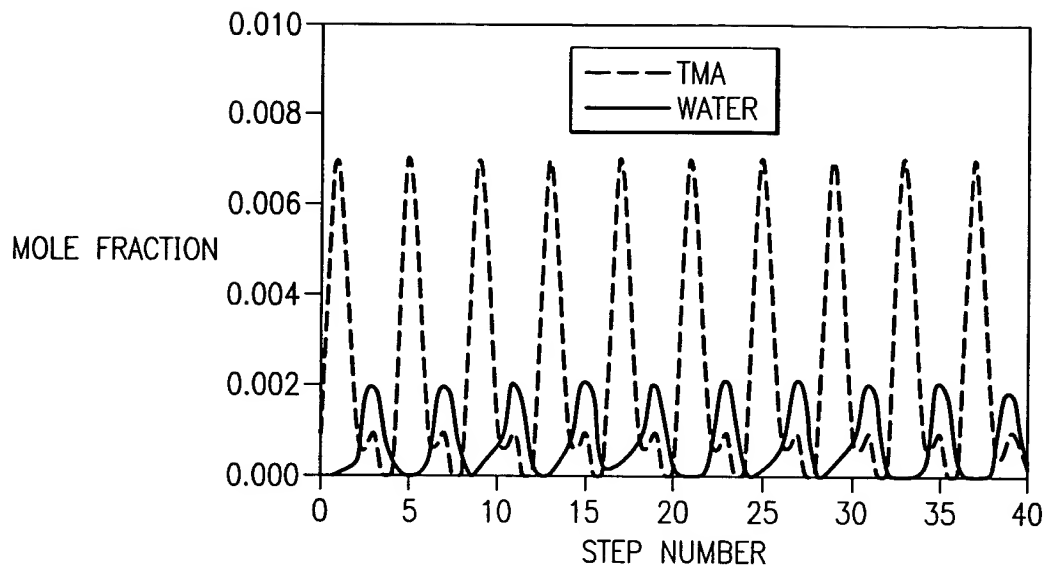


FIG. 4

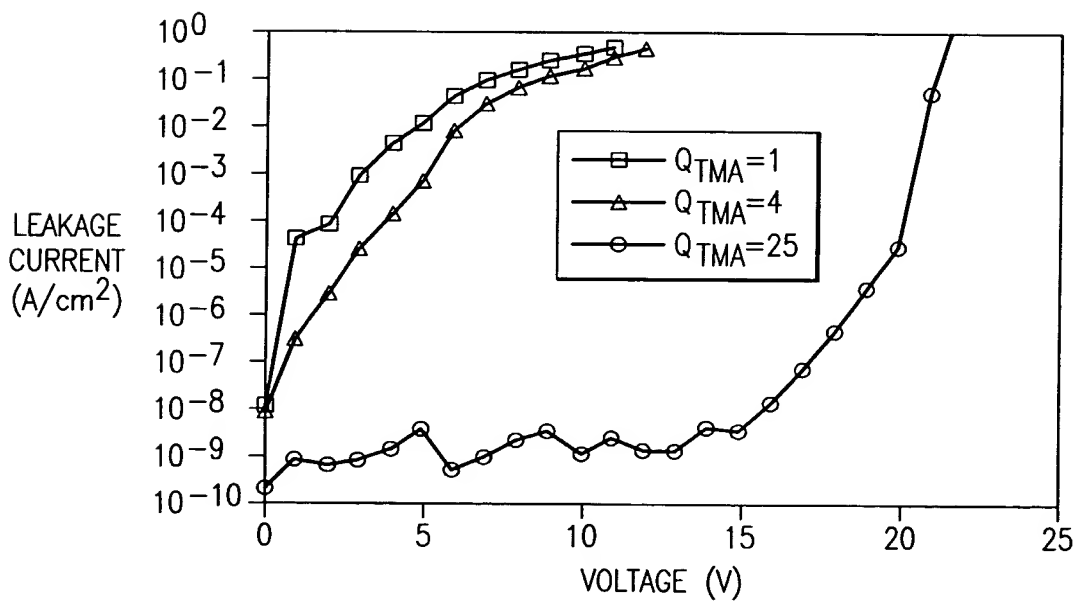


FIG. 5

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ATOMIC LAYER DEPOSITION FOR FABRICATING THIN FILMS

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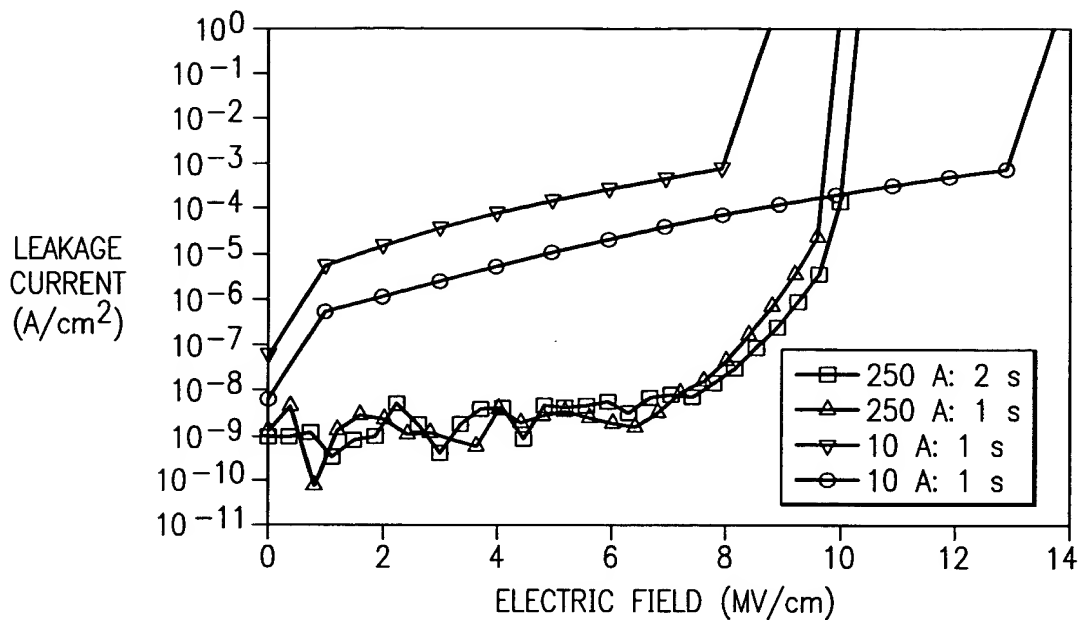


FIG. 6

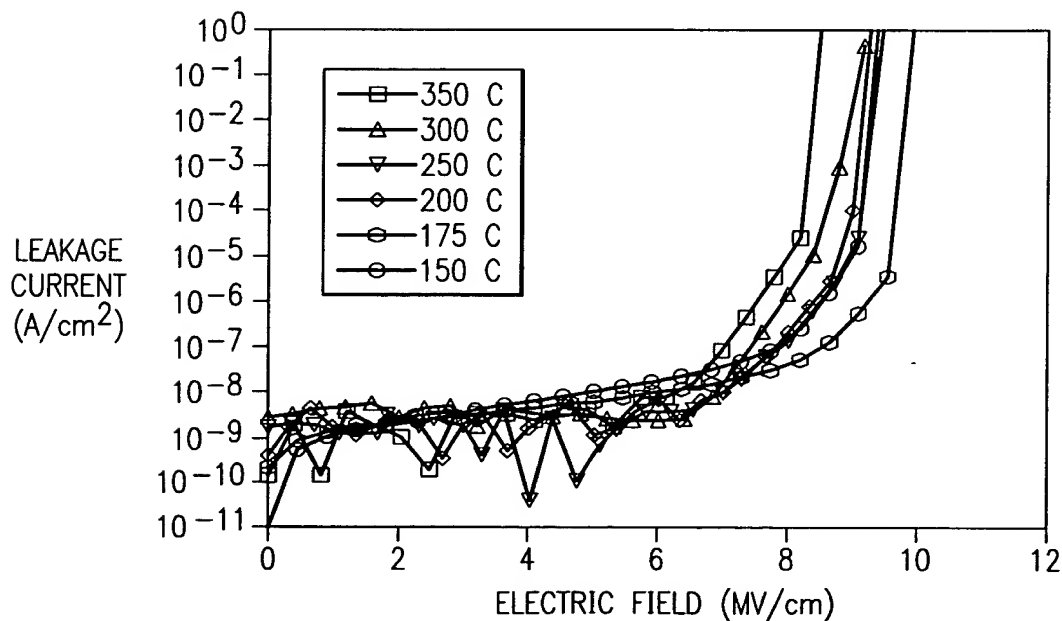


FIG. 7

APPROVED	O.G. FIG.	
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TOMIC LAYER DEPOSITION FOR ABRICATING THIN FILMS

inventor: Ajit P. Paranjpe, et al.
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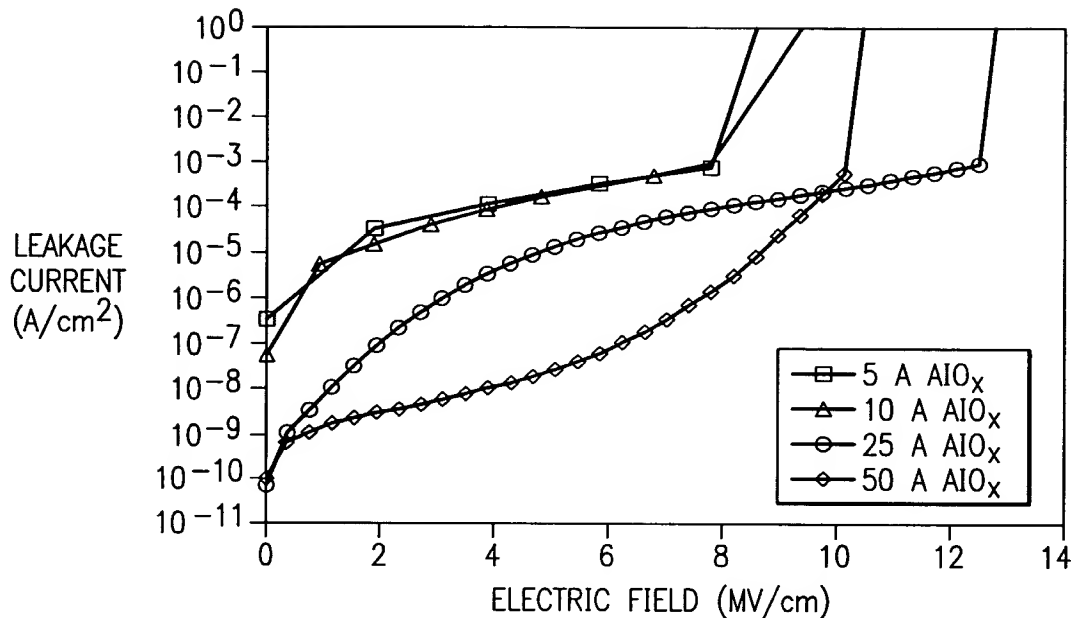


FIG. 8A

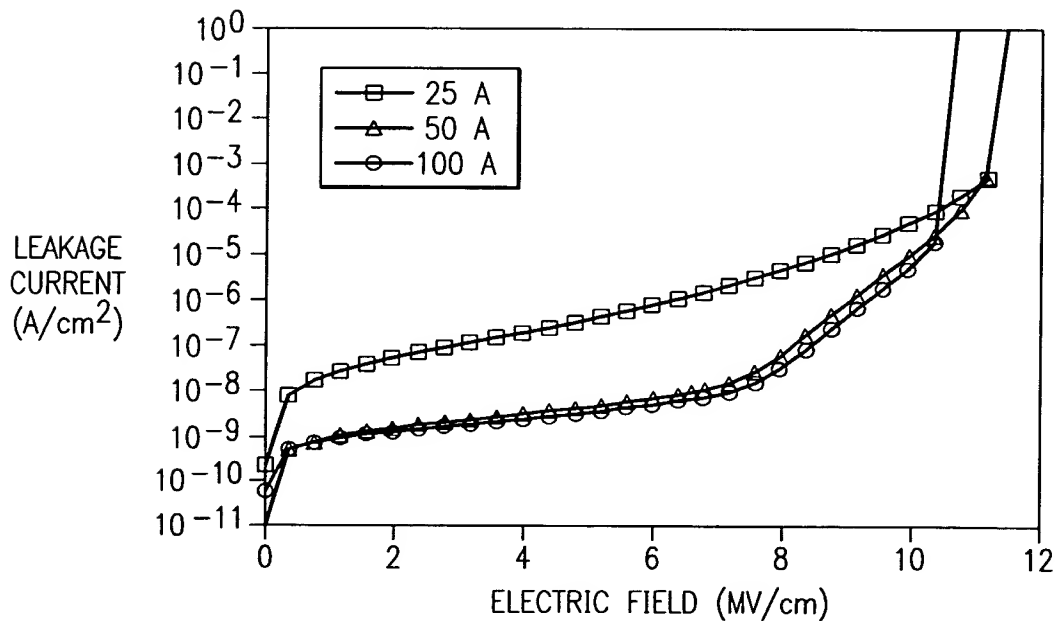


FIG. 8B

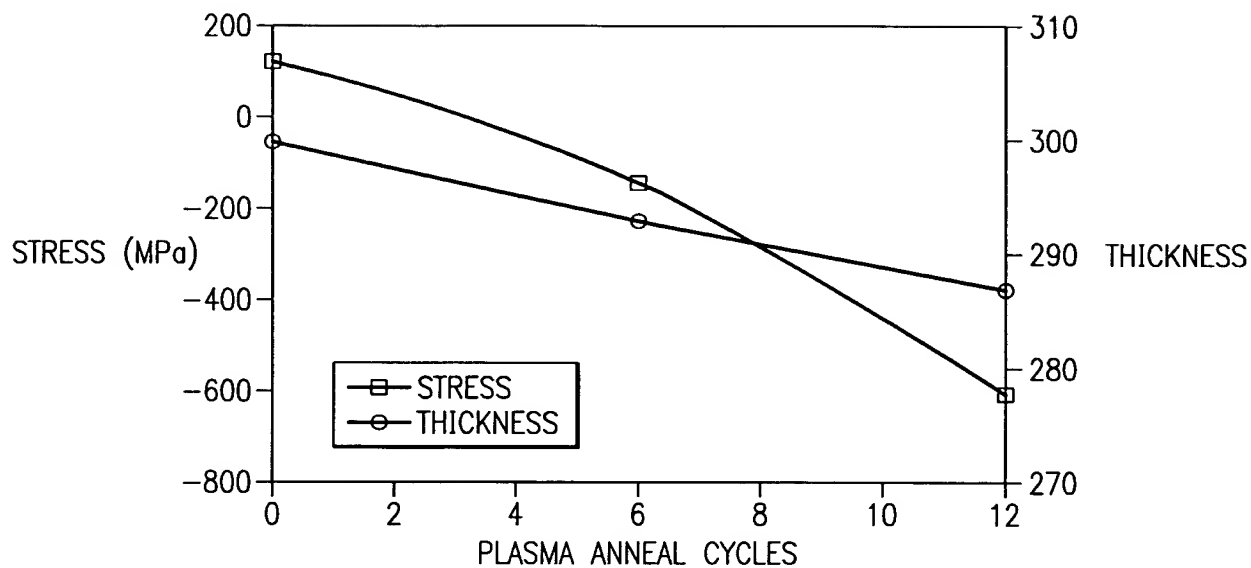


FIG. 9

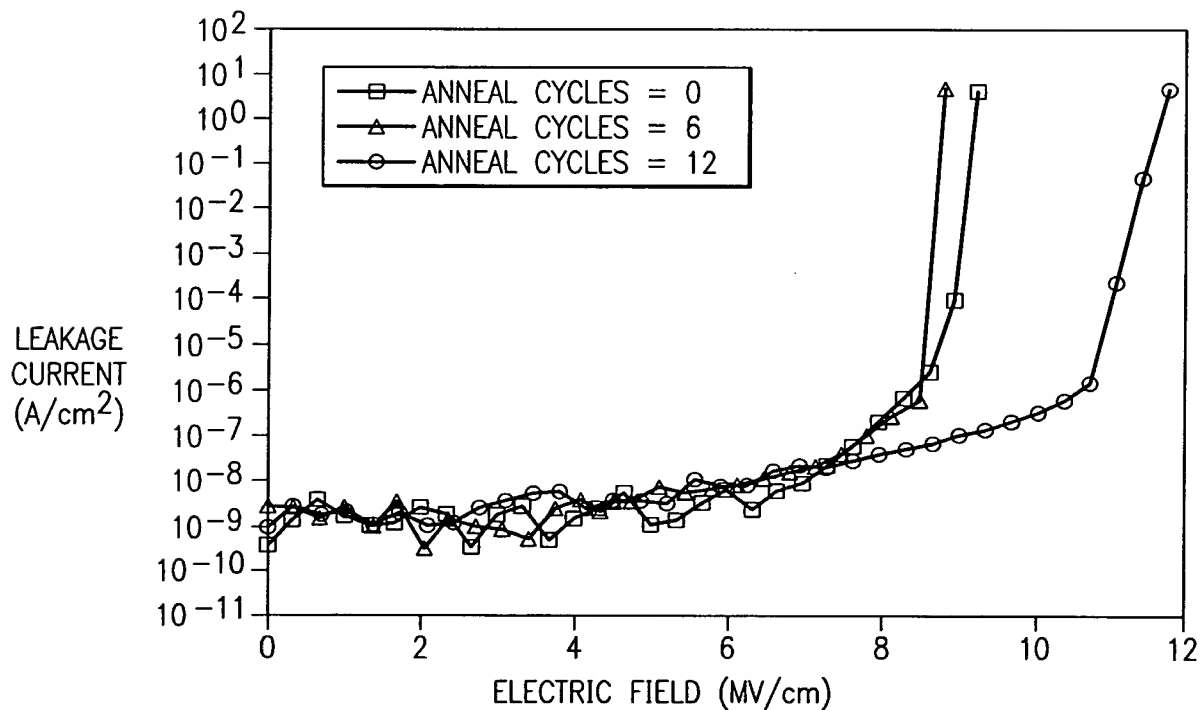


FIG. 10

APPROVED	O.G. FIG.
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TOMIC LAYER DEPOSITION FOR ABRICATING THIN FILMS

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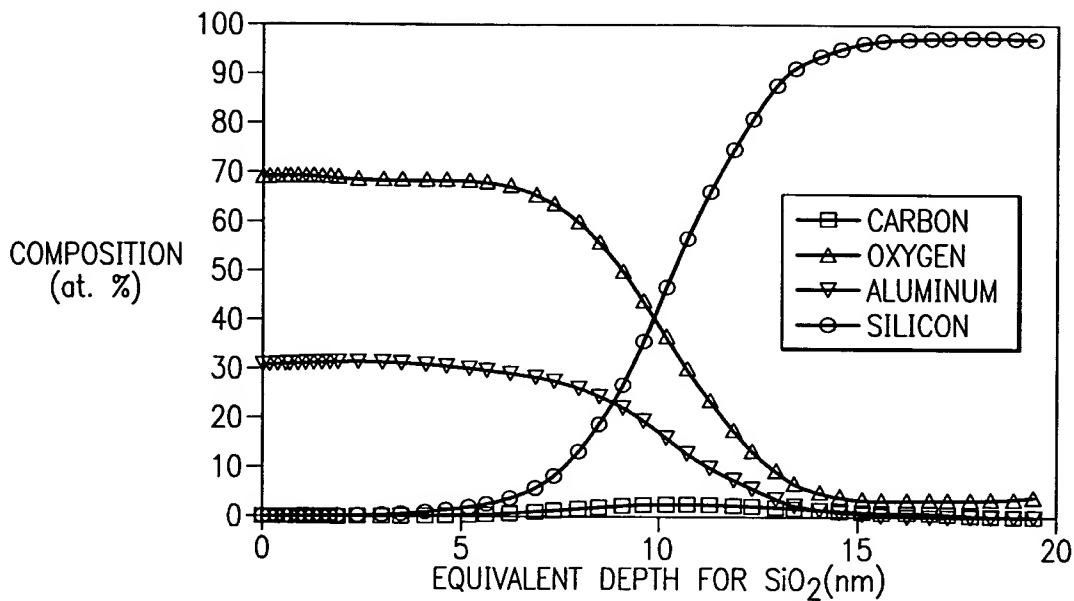


FIG. 11A

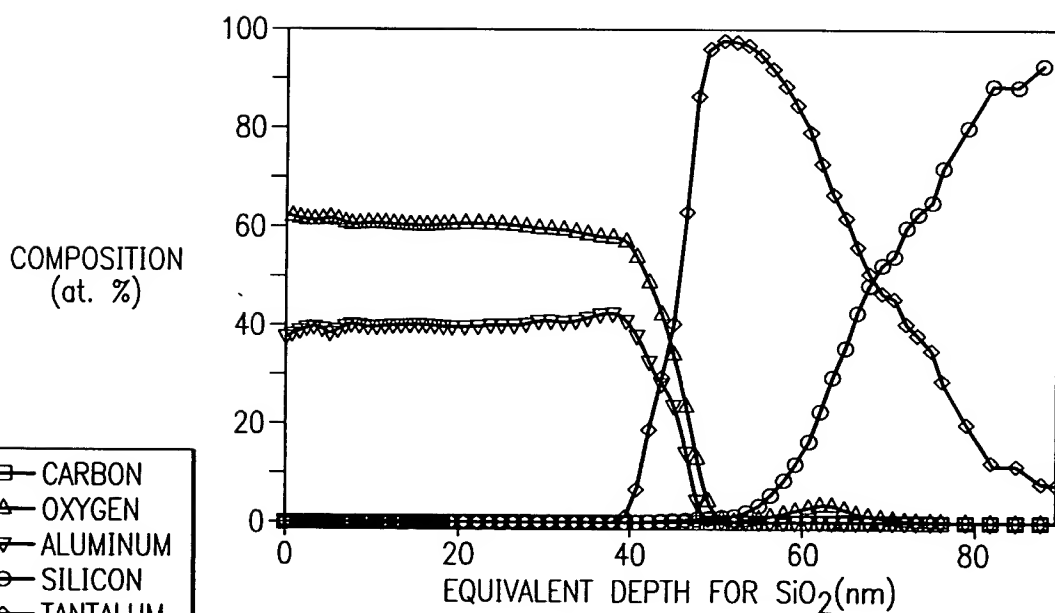


FIG. 11B